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U.S. Patent and Trademark Office: U.S. DEPARTMENT OF COMMERCE Paperwork Reduction Act of 1995, no persons are required to respond to a collection of information unless it contains a valid OMB control number, Complete if Known tute for form 1449A/PTO Application Number 09/766,596 **INFORMATION DISCLOSURE** Filing Date 1/23/2001 STATEMENT BY APPLICANT First Named Inventor Kato, et al. Art Unit 3749 **Examiner Name** P. Wilson luca se manu chaote se na of Sheet Attorney Docket Number 520,30414V22

			U.S. PATENT	DOCUMENTS	
Examiner Initials'	Cite No. ¹	Document Number Number-Kind Code ² (if known)	Publication Date MM-OD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
11/3/0	-	US- 5,536,128	7/16/1996	Shimoyashiro, et al.	
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Examiner Initials'	Cite No.1	Foreign Patent Document Country Code - Number - Kind Code - (if known) JP 64-036042	Publication Date MM-DD-YYYY 2/7/1989	Name of Patentee or Applicant of Cited Document Kokusai Electric Co., Ltd.	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear	T*
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		NON PATENT LITERATURE DOCUMENTS	
Examiner Initials*	Cite No.	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T ²
13105		S. Nakagawa, "Dry Etching", Drafts in Symposium of VLSI and FA Technology, April 1985, pages 1-14	
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